

IN THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Previously presented) An apparatus for processing a substrate with a fluid meniscus to be applied to a surface of the substrate, comprising:

a docking surface configured to be oriented adjacent to and beside an edge of the substrate, the docking surface being coplanar with the substrate, and providing a transition interface to allow the fluid meniscus to enter and exit the surface of the substrate, the transition interface being spaced apart from the substrate; and

a coupon magazine for holding the docking surface at one side and having a second side extend out to define the transition interface.
2. (Original) An apparatus for processing a substrate as recited in claim 1, wherein the docking surface defines a docking station for the fluid meniscus.
3. (Canceled)
4. (Previously presented) An apparatus for processing a substrate as recited in claim 1, wherein the docking surface has a radial contour at the second side that defines the transition interface, and the radial contour of the docking surface is configured to match a radial contour of the substrate at a segment of the substrate that is less than a circumference of the substrate.

5. (Previously presented) An apparatus for processing a substrate with a fluid meniscus to be applied to a surface of the substrate, comprising:

a docking surface configured to be placed adjacent to and beside an edge of the substrate, the docking surface being coplanar with the substrate, and providing a transition interface to allow the fluid meniscus to enter and exit the surface of the substrate, the transition interface being spaced apart from the substrate; and

a coupon magazine for holding the docking surface at one side and having a second side extend out to define the transition interface, and the coupon magazine includes a top portion and a bottom portion for holding the docking surface;

wherein the docking surface has a radial contour at the second side that defines the transition interface, and the radial contour of the docking surface is configured to match a radial contour of the substrate at a segment of the substrate that is less than a circumference of the substrate.

6. - 8. (Canceled).

9. (Original) An apparatus for use in processing a substrate as recited in claim 5, wherein the docking station is a quartz material.

10. (Original) An apparatus for use in processing a substrate as recited in claim 5, wherein the docking station is a hydrophilic material.

11. (Previously presented) An apparatus for use in processing a substrate as recited in claim 5, further comprising,

a coupon magazine mount configured to hold the coupon magazine; and

rollers for positioning the substrate so that the substrate is spaced apart from the docking surface and coplanar.

12. (Original) An apparatus for use in processing a substrate as recited in claim 5, further comprising,

a leveling mechanism configured to move the docking station to be substantially coplanar with the substrate.

13. (Original) An apparatus for use in processing a substrate as recited in claim 12, wherein the leveling mechanism is configured to move the docking station in a vertical plane.

14. (Original) An apparatus for use in processing a substrate as recited in claim 12, wherein the leveling mechanism includes a screw configured to move a ball detent vertically.

15. (Original) An apparatus for use in processing a substrate as recited in claim 5, wherein the coupon magazine includes a sight window.

16.-20. (Canceled)

21. (Previously presented) An apparatus for processing a substrate, comprising:

a coupon assembly for holding a docking station, the docking station having a curved docking surface for defining a transition interface to a radial segment of the substrate; and

a coupon magazine mount for holding the coupon assembly, the coupon magazine mount defined to hold the curved docking surface of the docking station in an adjacent and coplanar orientation to a surface of the substrate.

22. (Previously presented) The apparatus as recited in claim 21, further comprising:

a leveling mechanism being part of the coupon magazine mount, the leveling mechanism providing adjustment of the docking station so as to place curved docking surface in the coplanar orientation.

23. (Previously presented) The apparatus as recited in claim 21, wherein the docking station has an exterior portion and an interior portion that defines an opening, the exterior portion having sides for connecting to the coupon assembly and a side that includes the curved docking surface.

24. (Previously presented) The apparatus as recited in claim 21, wherein the docking station has a thickness that approximately matches a thickness of the substrate.

25. (Previously presented) The apparatus as recited in claim 23, wherein the coupon assembly includes a top portion and a bottom portion, and the top and bottom portion configured to hold the sides for connecting to the coupon assembly.

26. (Previously presented) The apparatus as recited in claim 21, wherein the adjacent orientation defines a separation between the substrate and the curved docking surface.

27. (Previously presented) The apparatus as recited in claim 26, wherein the separation is between about 0.001 mm and about 0.1 mm.

28. (Previously presented) The apparatus as recited in claim 21, further comprising:

rollers for positioning the substrate so that the substrate is spaced apart from the docking surface and in the coplanar orientation.